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Errata: Model for thickness dependence of mobility and concentration in highly conductive zinc oxide

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This article [*Opt. Eng.* **52**(3), 033801 (2013)] was originally published on 13 March 2013 with an error in the author list. The last author's name was misspelled "Surhariadi." The correct spelling appears above.

The paper was corrected on 23 March 2017.